

FIG. 1

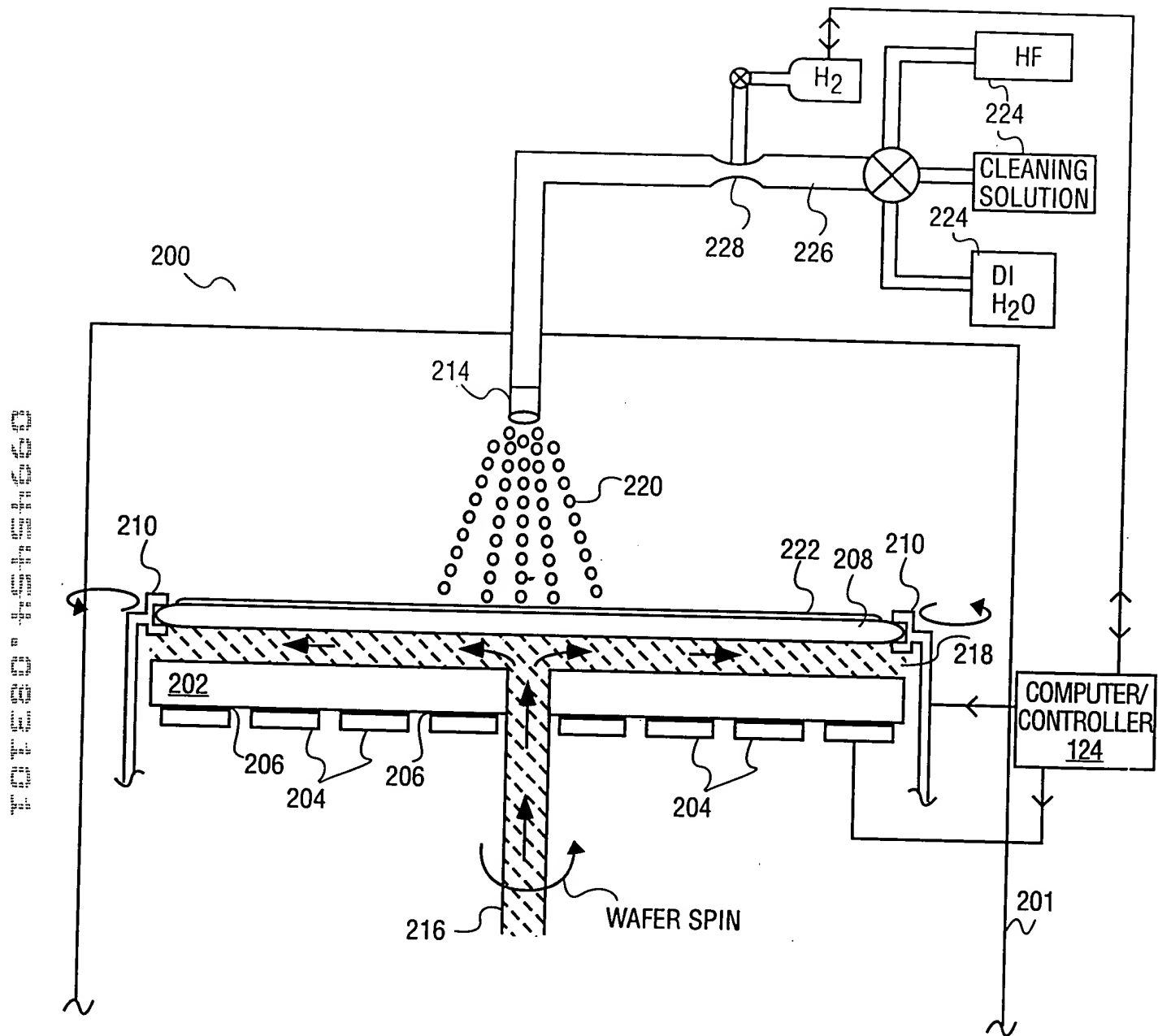


FIG. 2A

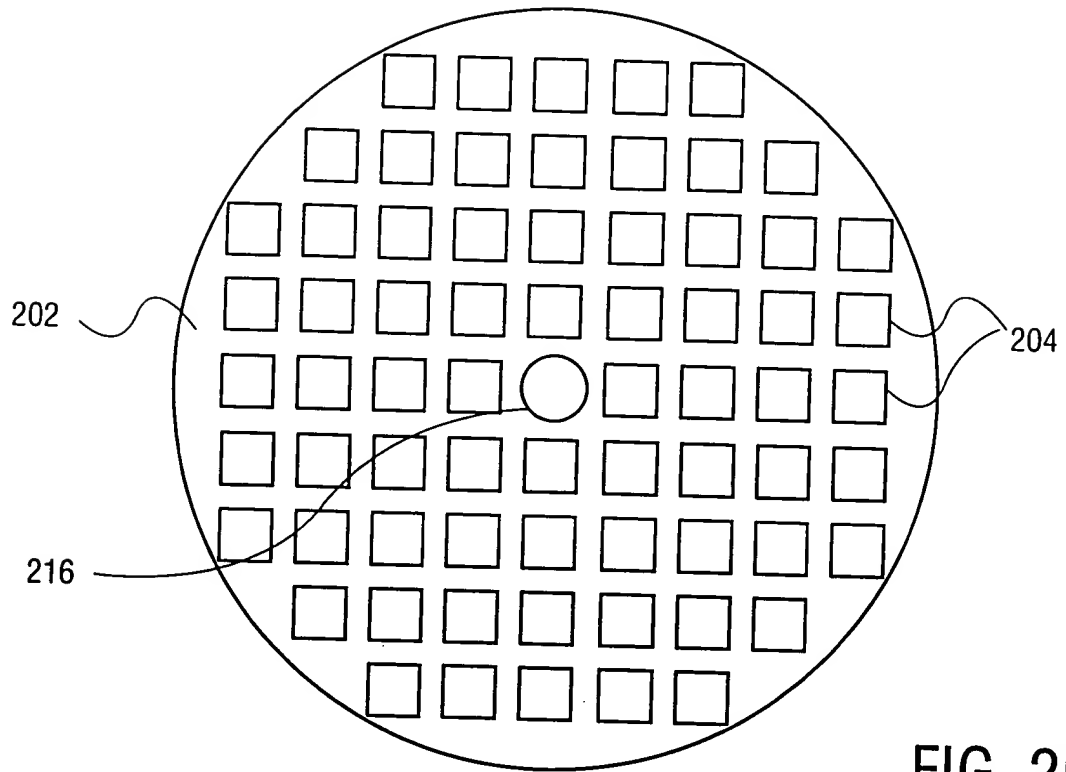


FIG. 2B

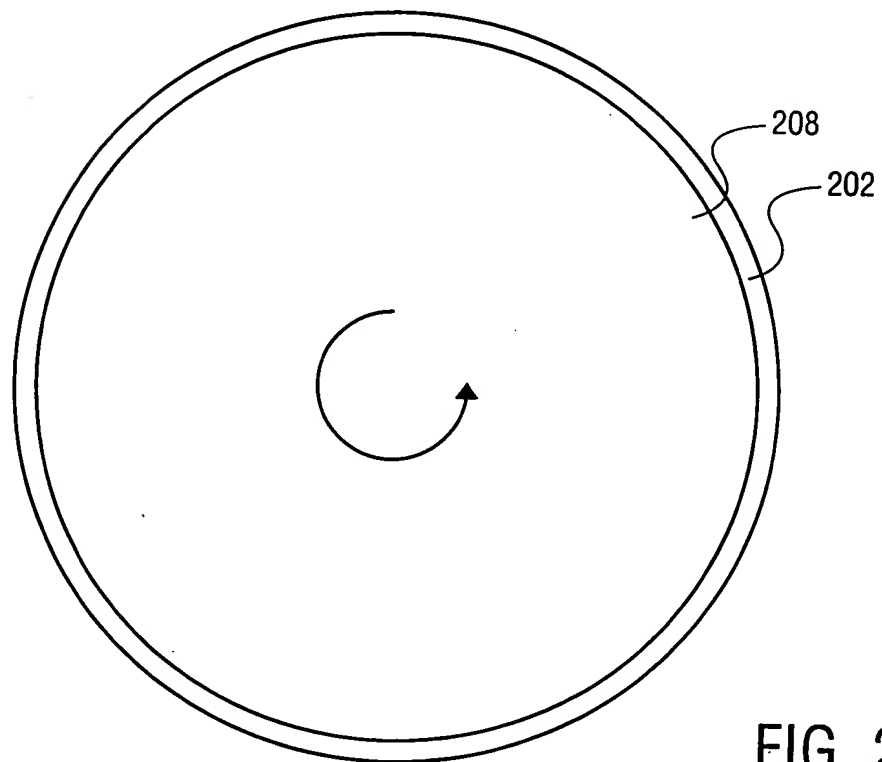


FIG. 2C

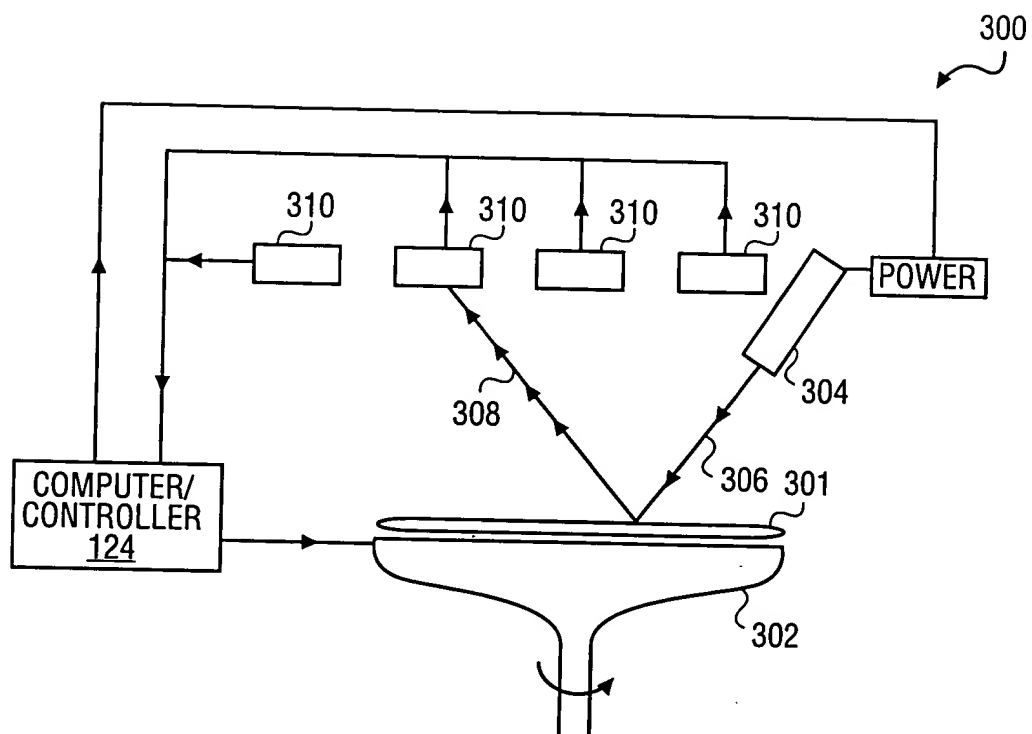


FIG. 3

FIG. 4 is a schematic diagram of a microwave cleaning system.

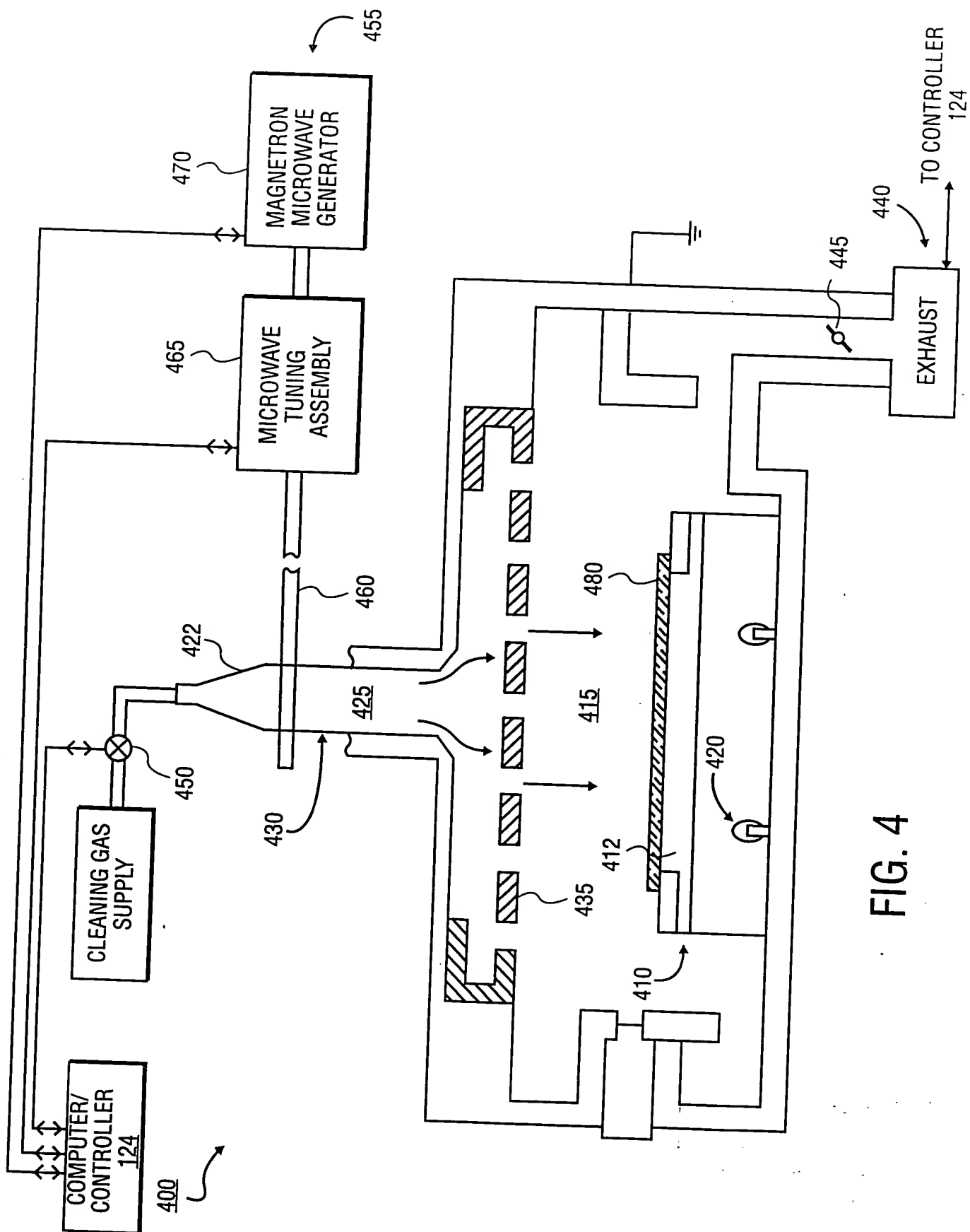


FIG. 4

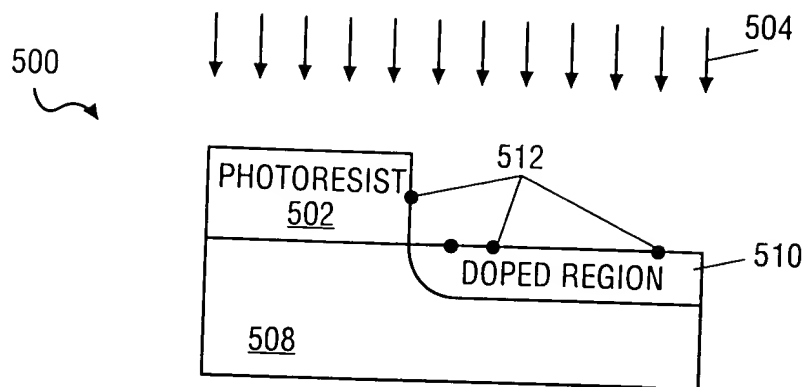


FIG. 5A

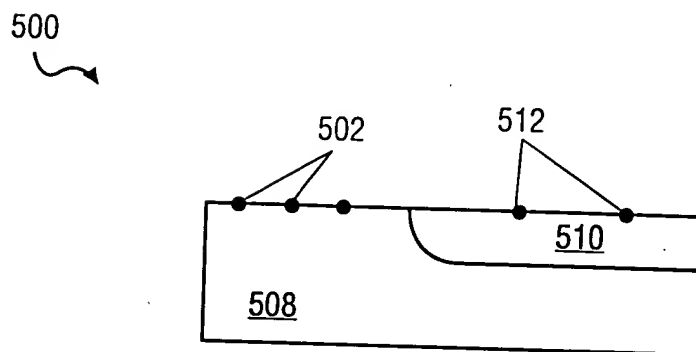


FIG. 5B

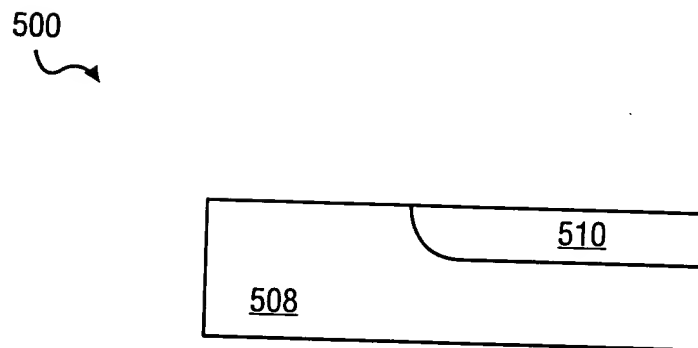


FIG. 5C

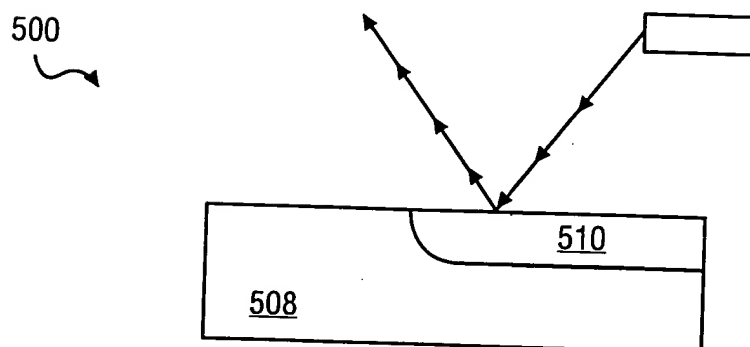


FIG. 5D

FIG. 6

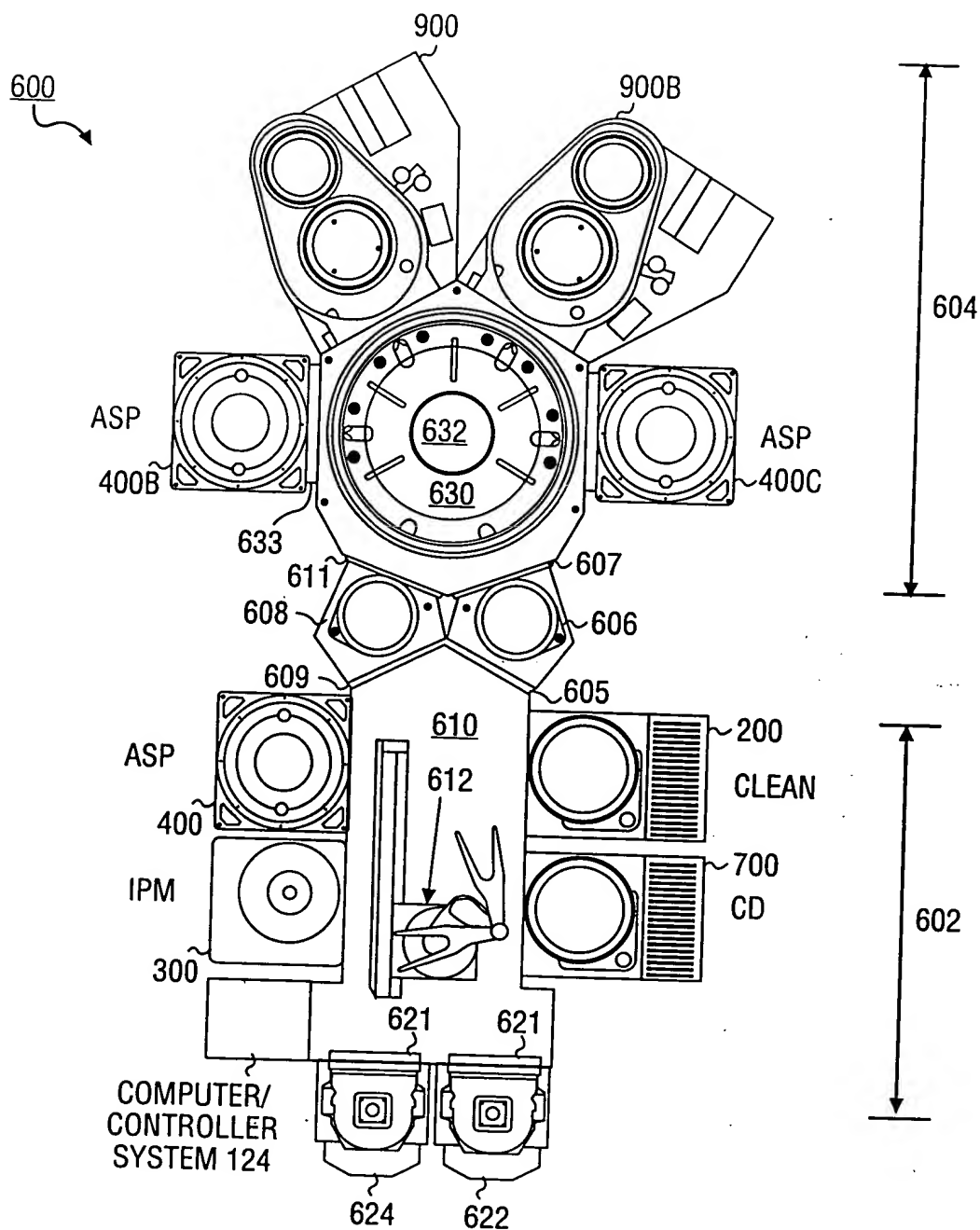


FIG. 6

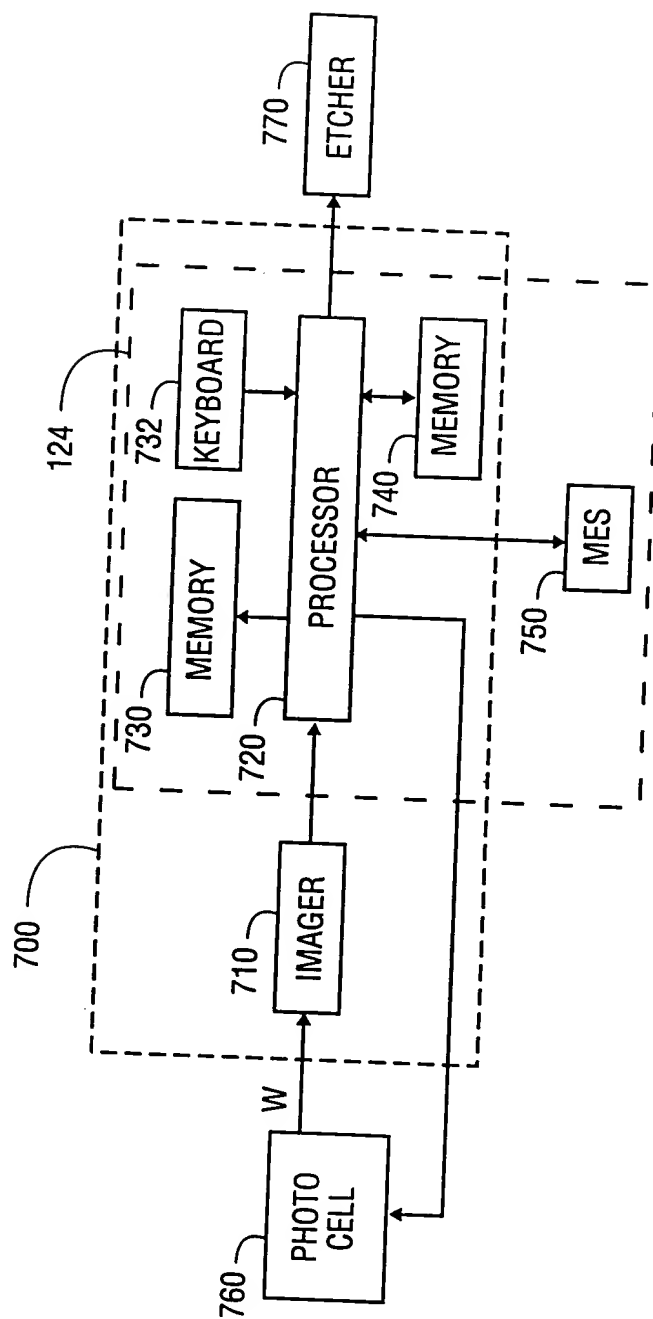


FIG. 7

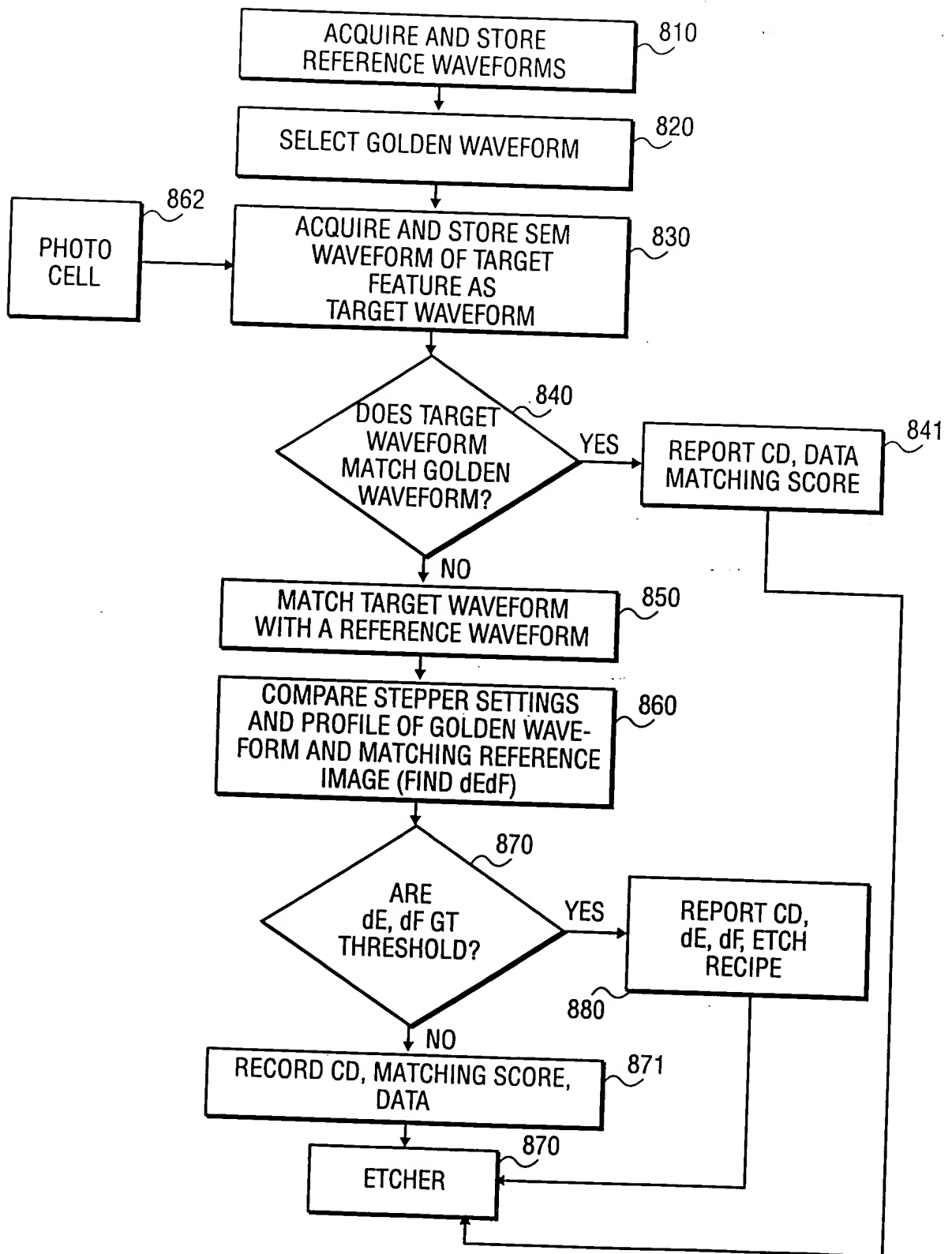


FIG. 8A

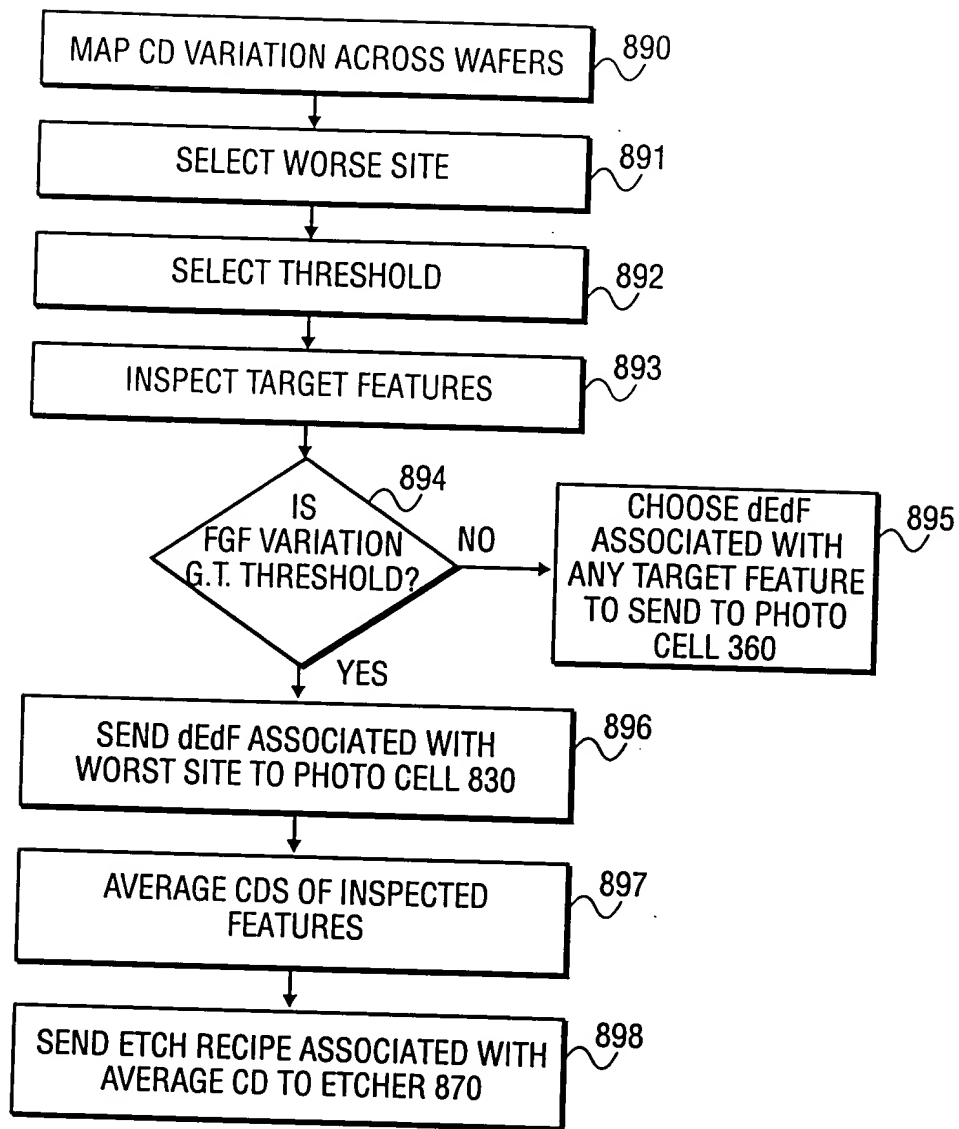


FIG. 8B

FIG. 9 is a schematic diagram of a plasma processing system 900. The system includes a chamber 910 with a curved wall 990 and a floor 940. A process gas source 962 is connected to the chamber 910 via a line 964. An electrode power supply 985 is connected to the chamber 910 via a line 985. A coil power supply 170 is connected to the chamber 910 via an RF match network. An exhaust system 995 is connected to the chamber 910 via a line 995. A computer/controller 124 is connected to the process gas source 962, the electrode power supply 985, and the RF match network. The chamber 910 contains a substrate 950 with a top surface 930 and a bottom surface 955. A plasma 145 is generated in the chamber 910. The system is controlled by the computer/controller 124.

900

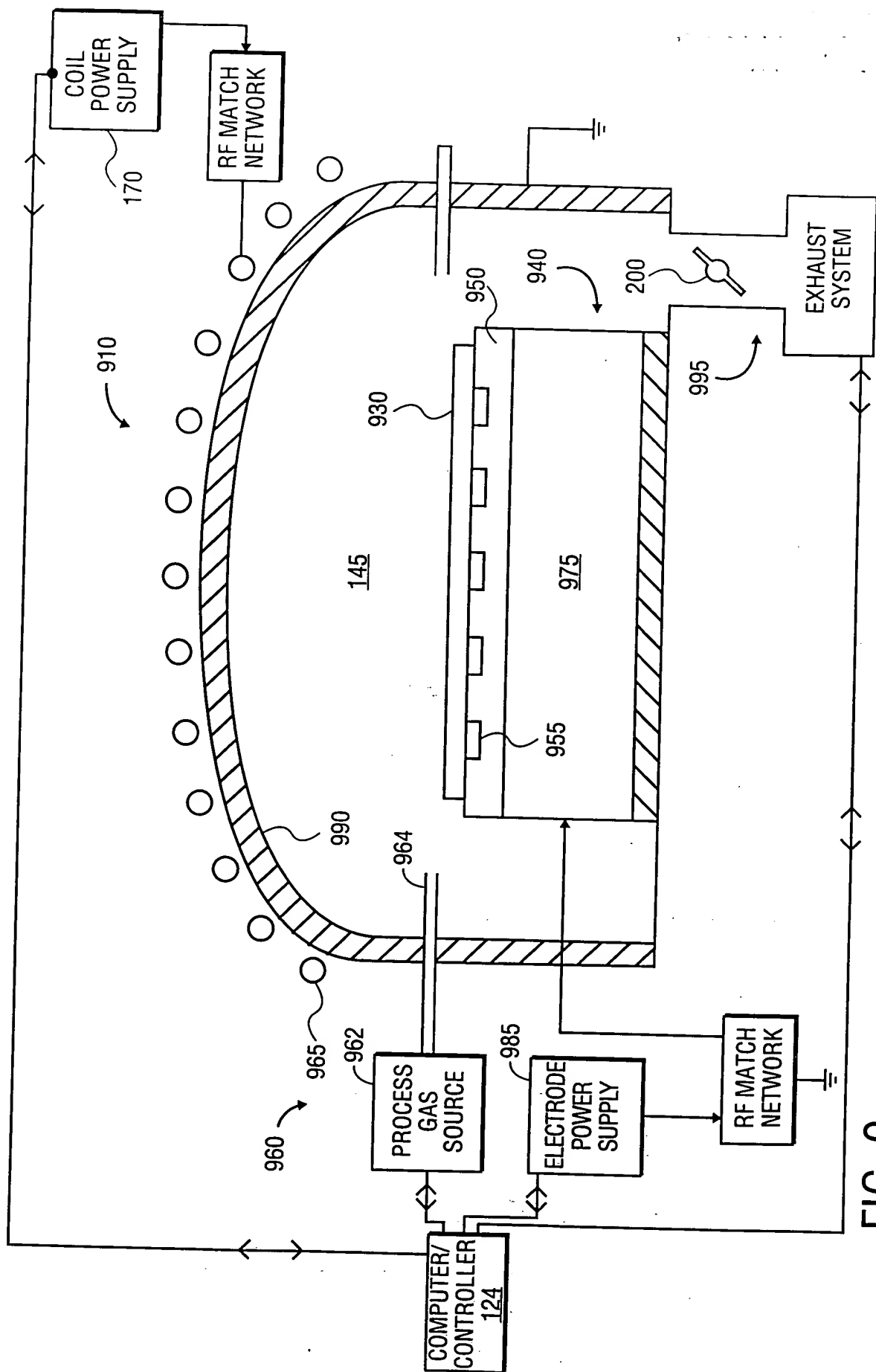


FIG. 9

RESIST TRIMMING

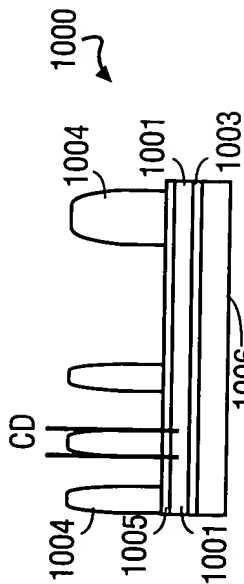


FIG. 10A

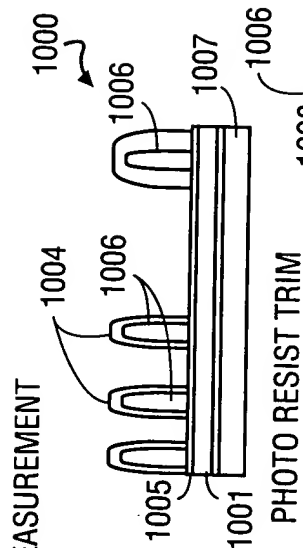


FIG. 10B

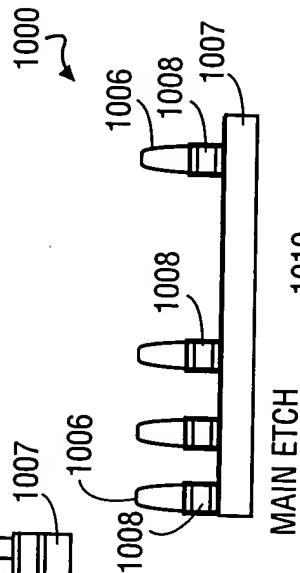


FIG. 10C

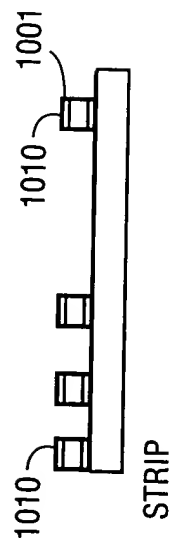


FIG. 10D

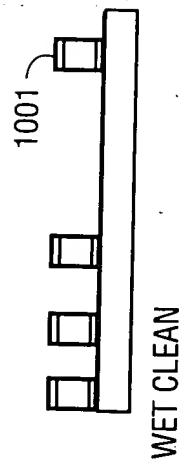


FIG. 10E

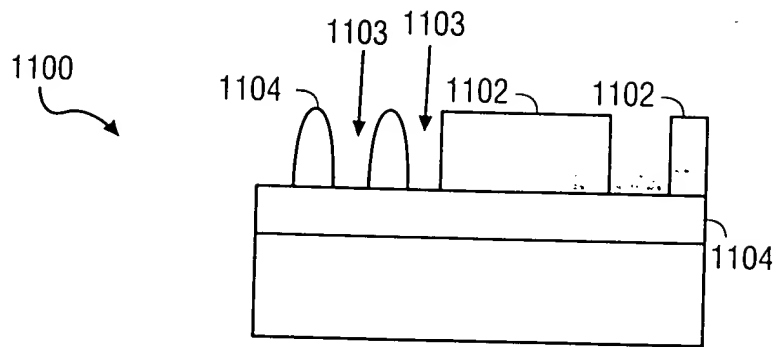


FIG. 11A

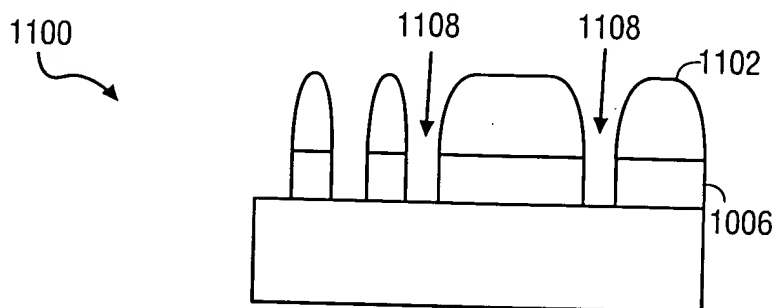


FIG. 11B

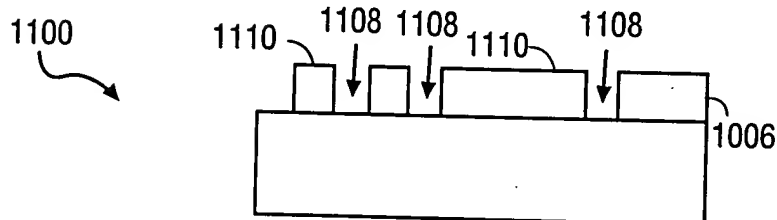


FIG. 11C

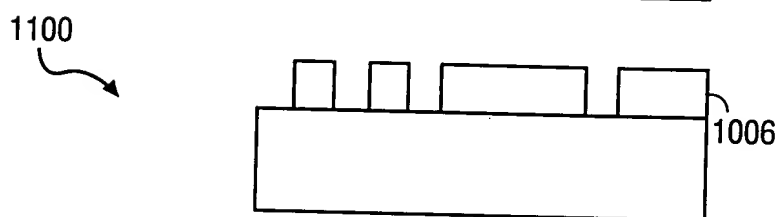


FIG. 11D

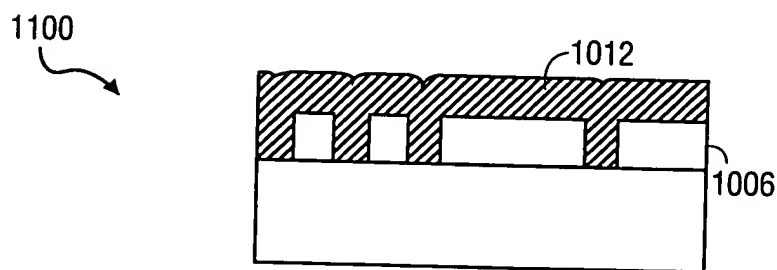


FIG. 11E

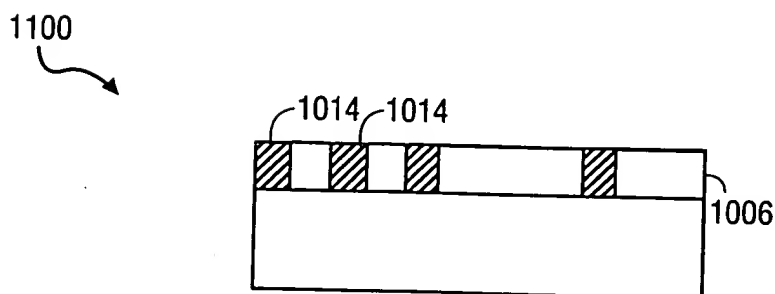


FIG. 11F

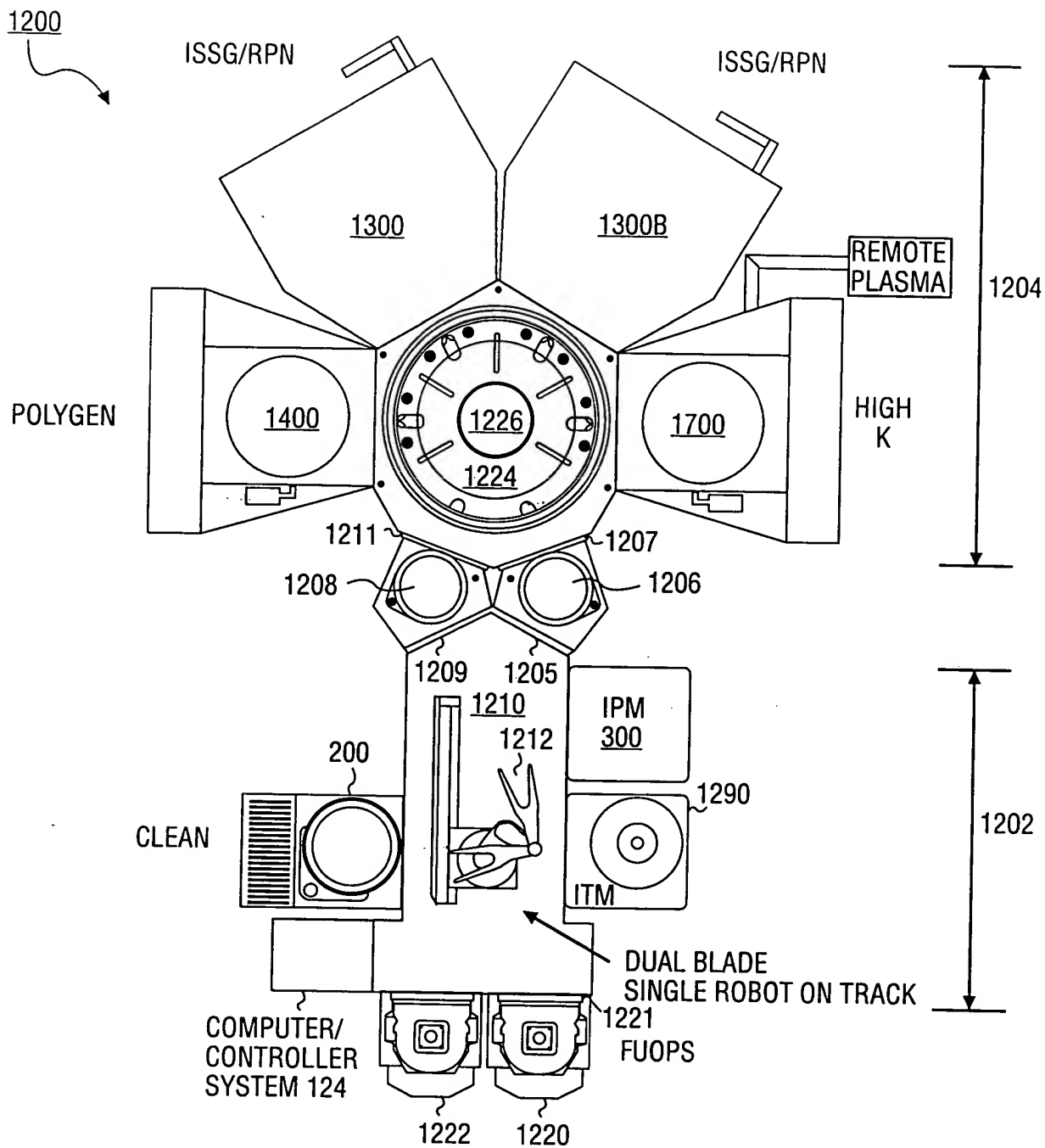


FIG. 12

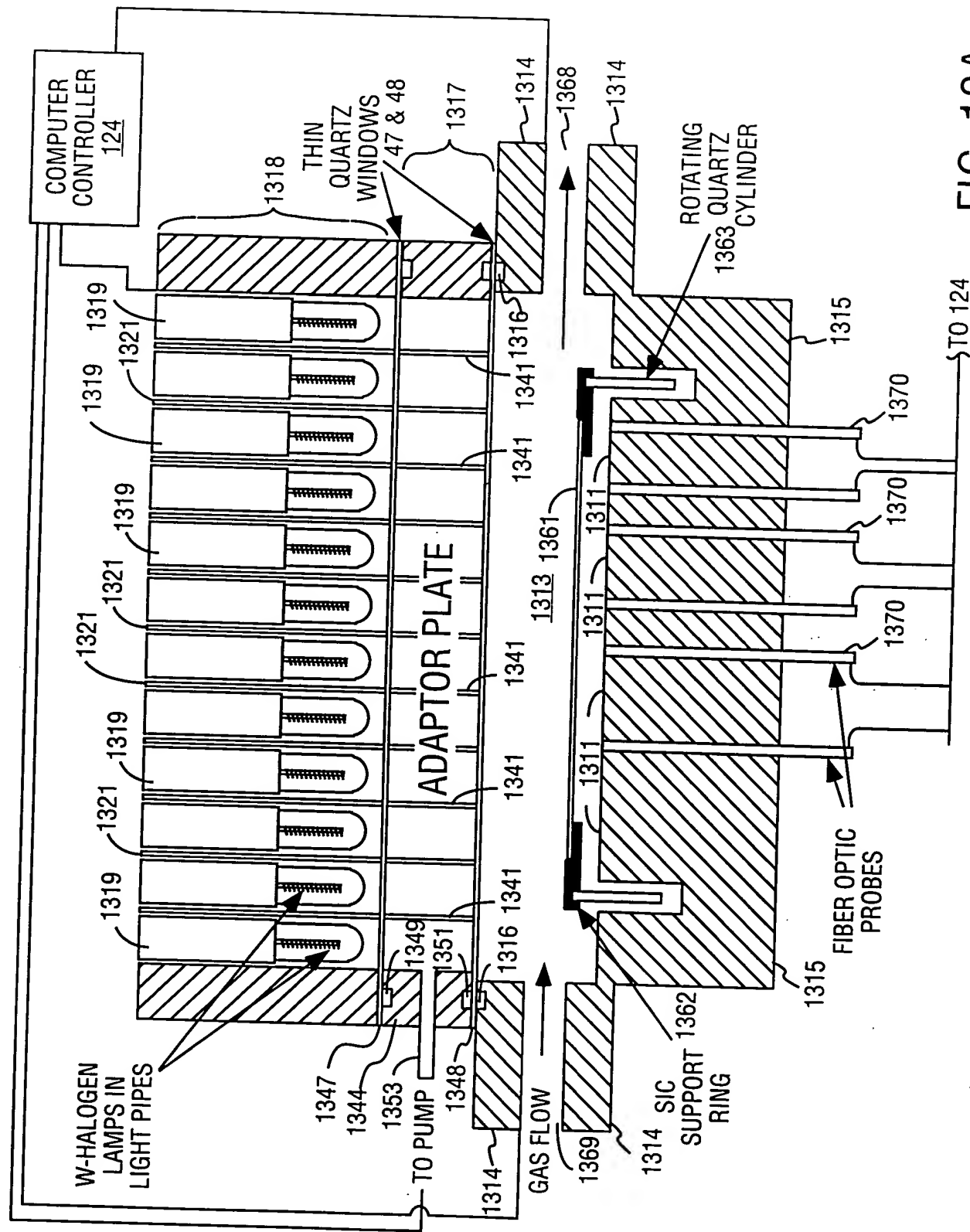


FIG. 13A

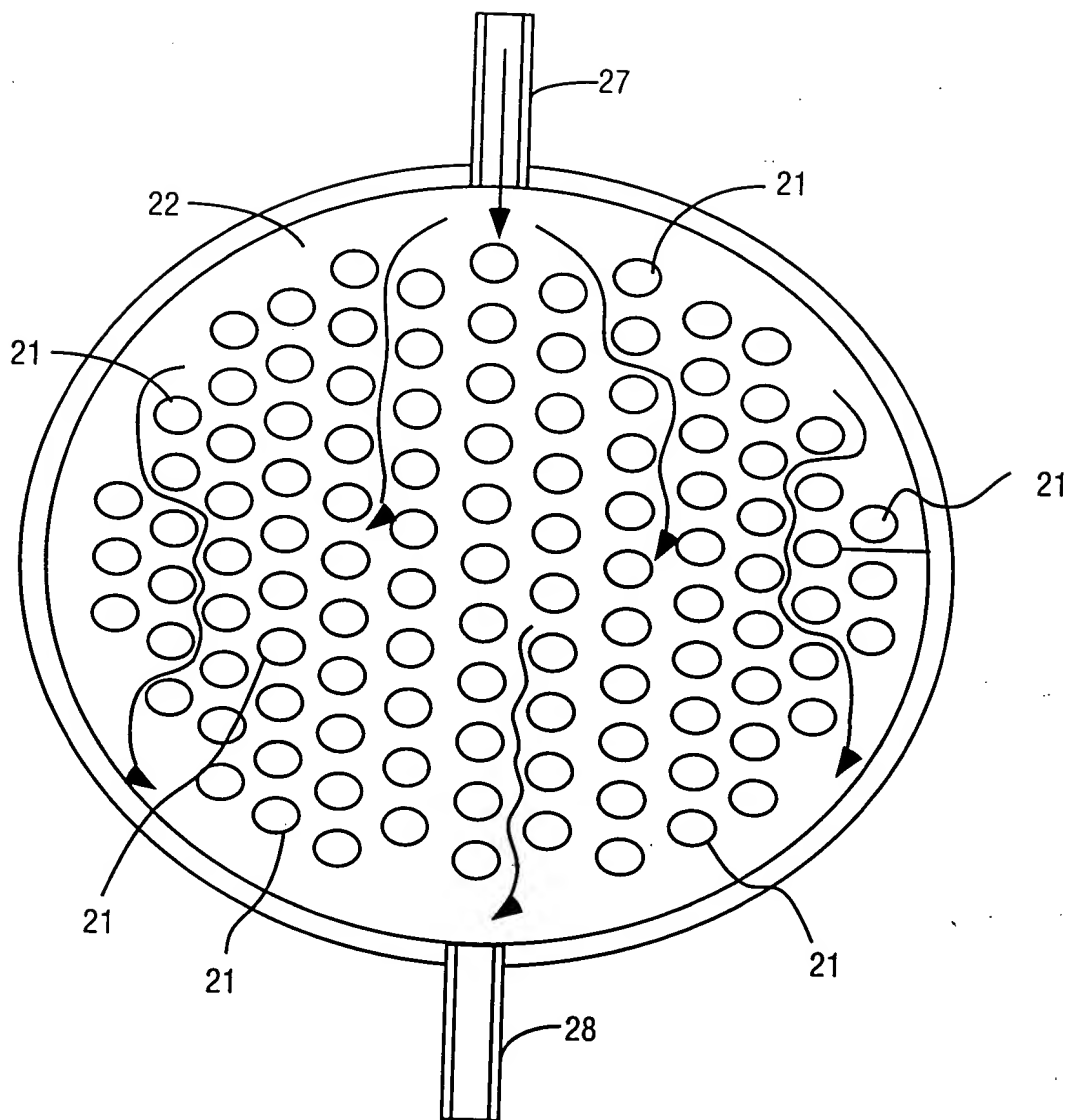


FIG. 13B

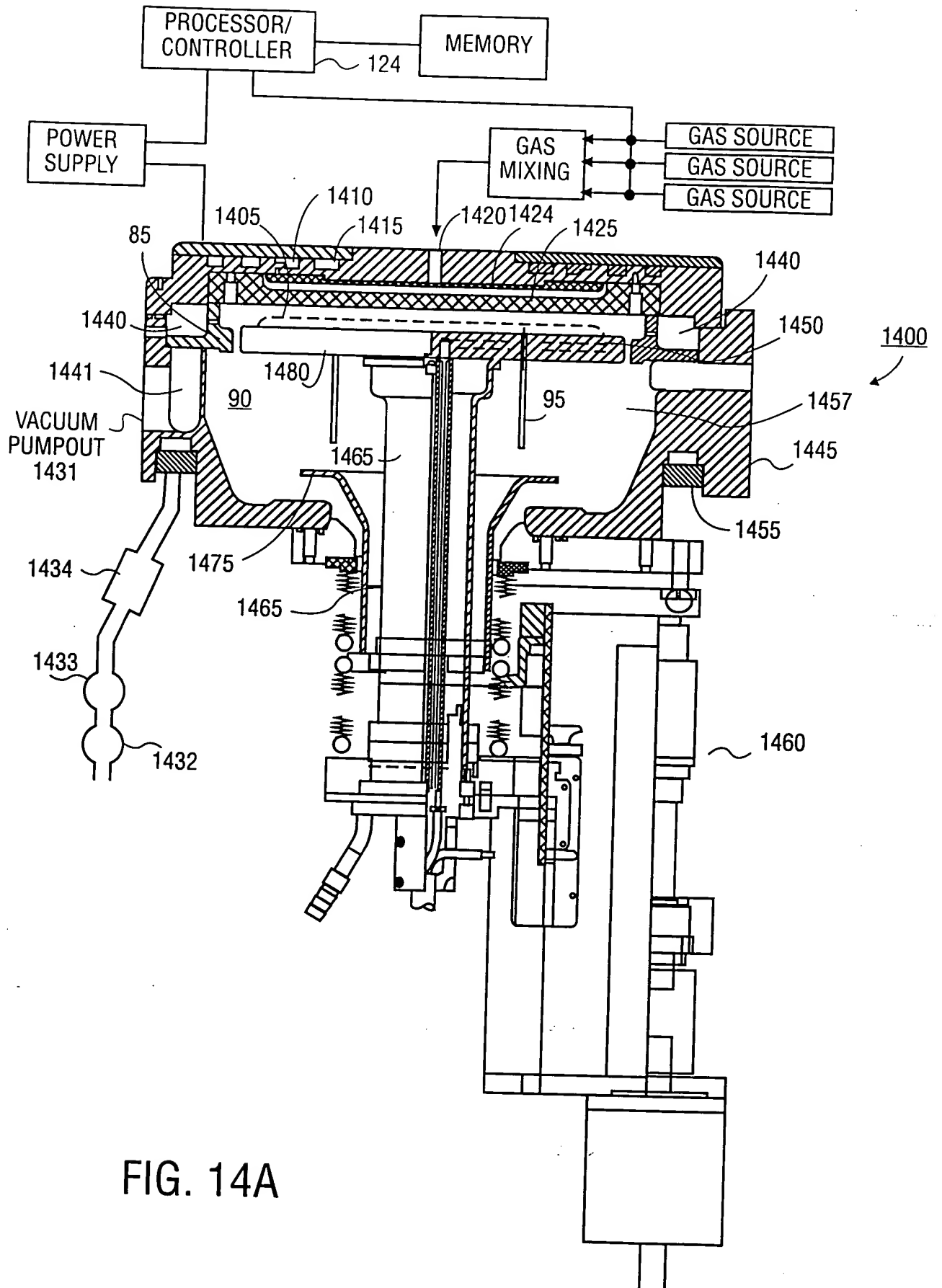


FIG. 14A

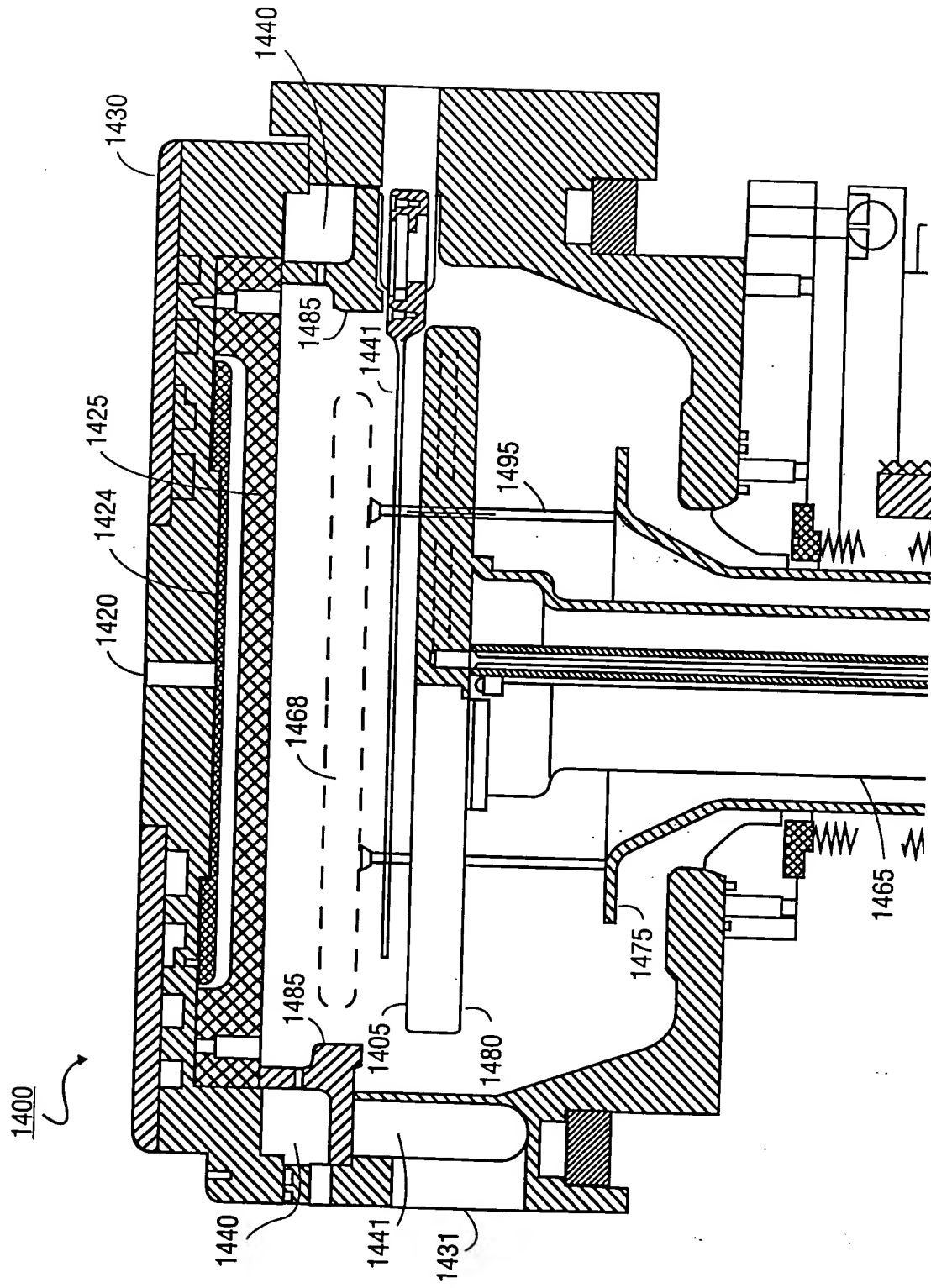


FIG. 14B

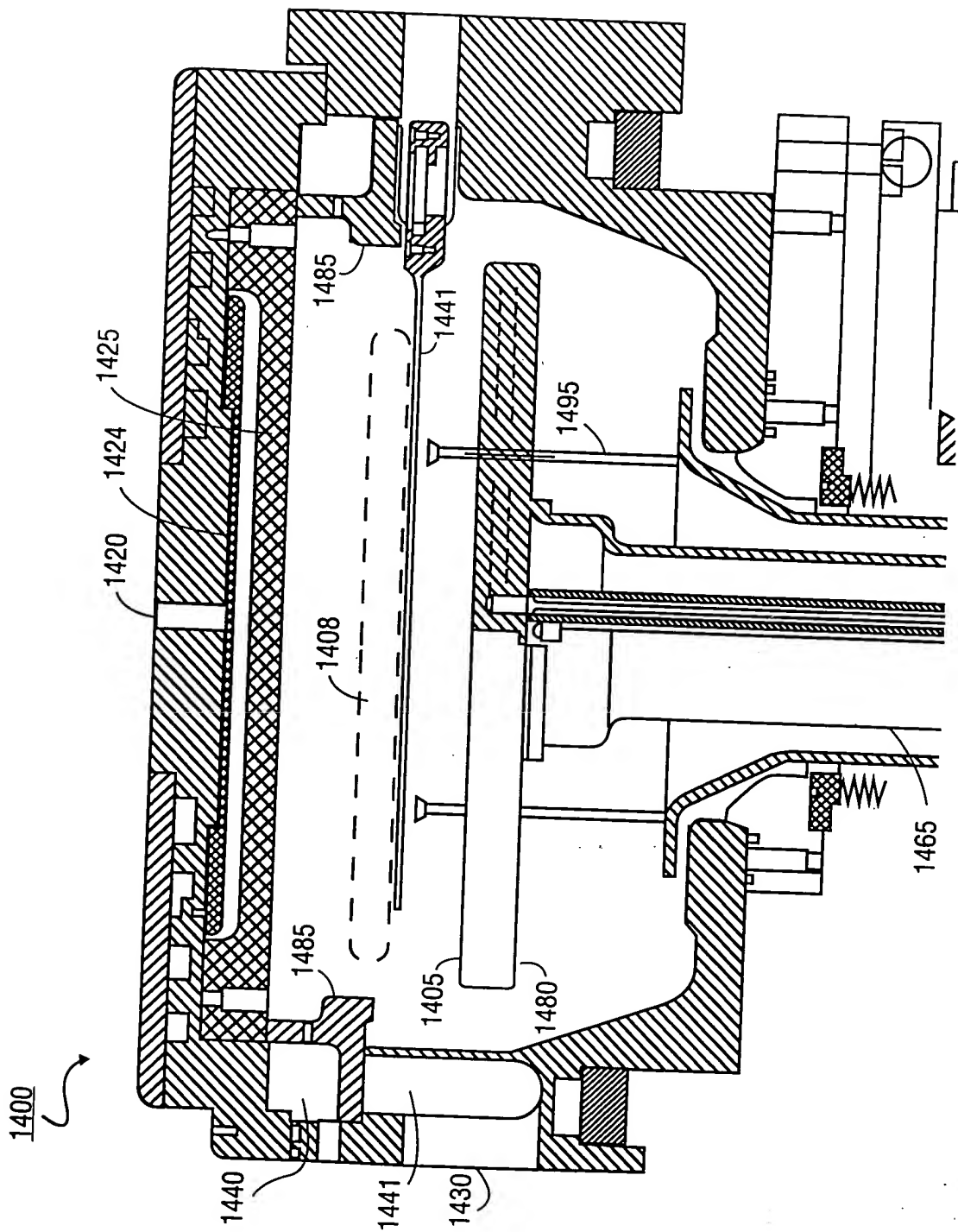


FIG. 14C

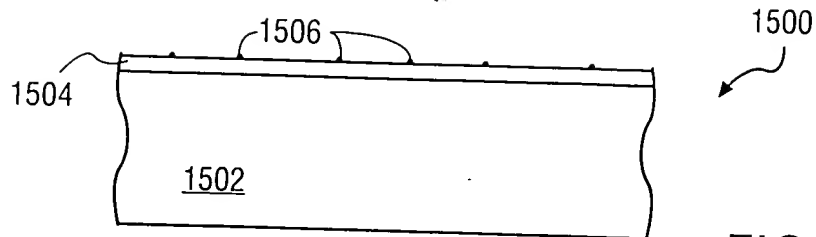


FIG. 15A

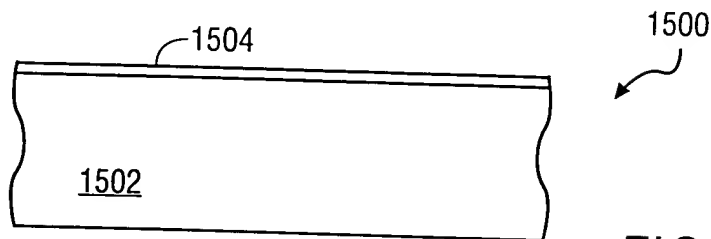


FIG. 15B

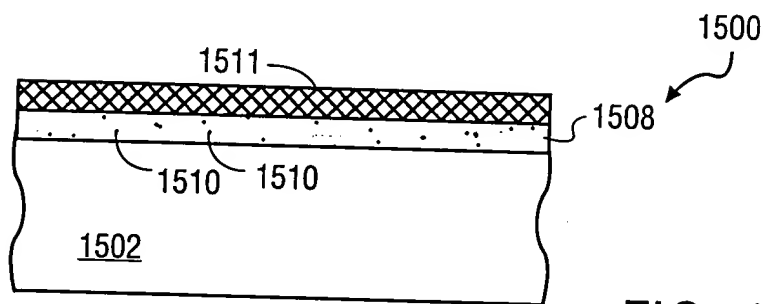


FIG. 15C

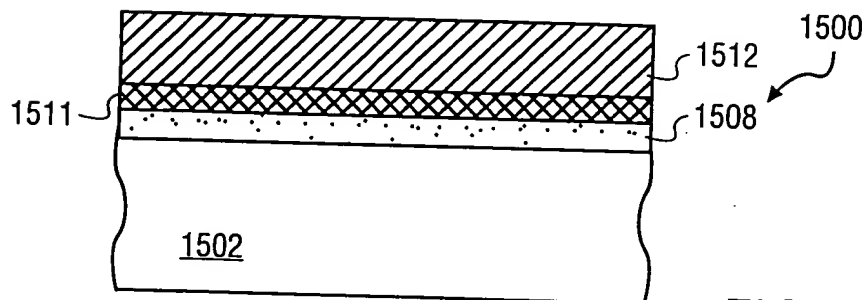


FIG. 15D

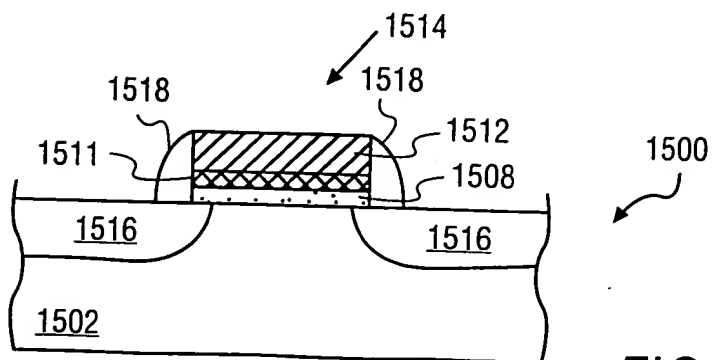


FIG. 15E

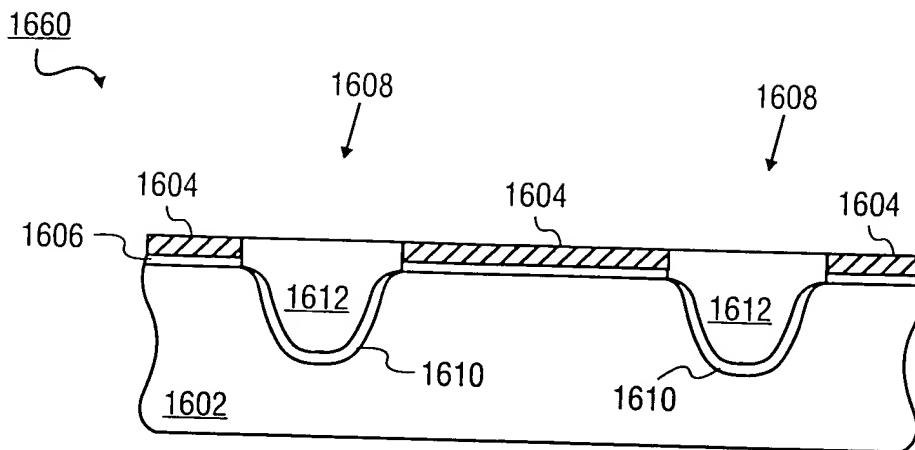


FIG. 16A

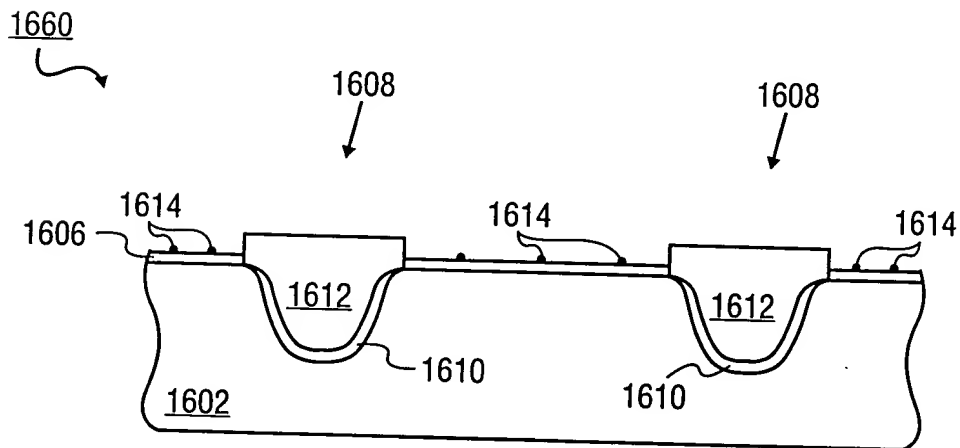


FIG. 16B

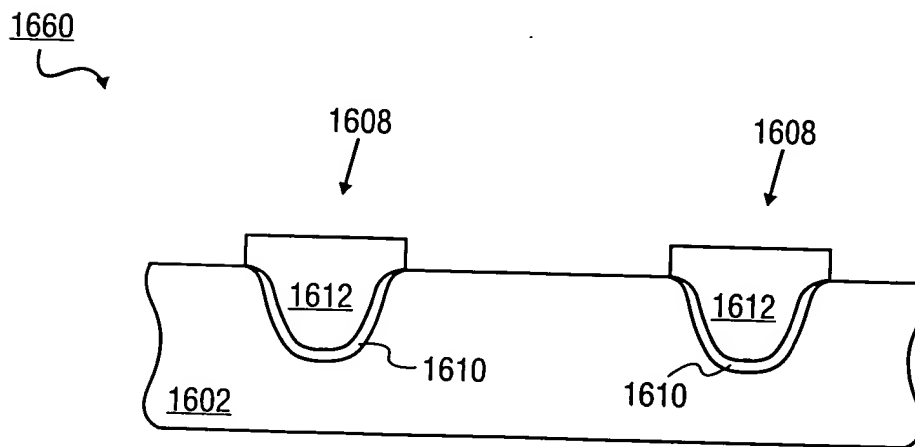


FIG. 16C

Figure 17A

1700

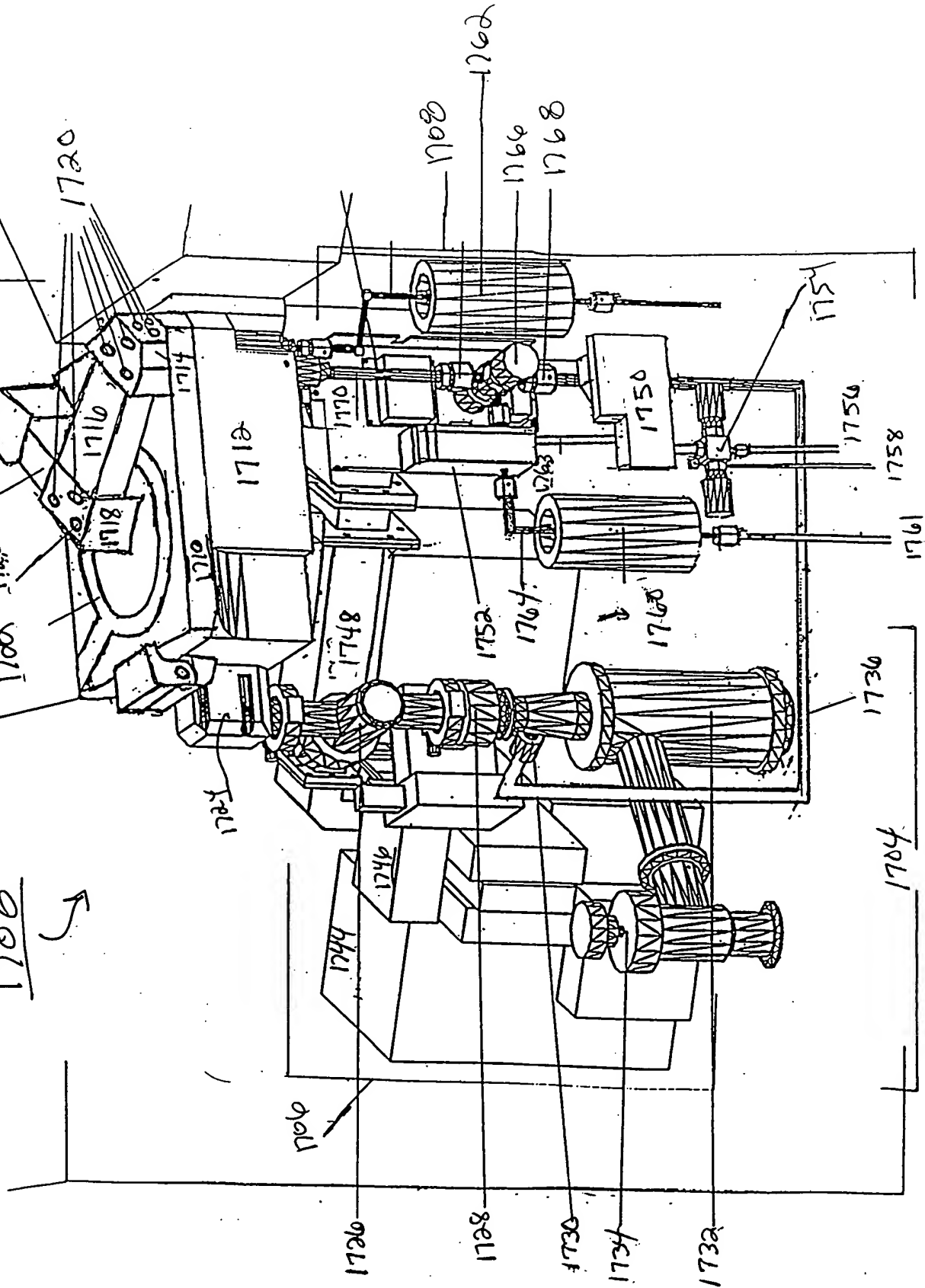
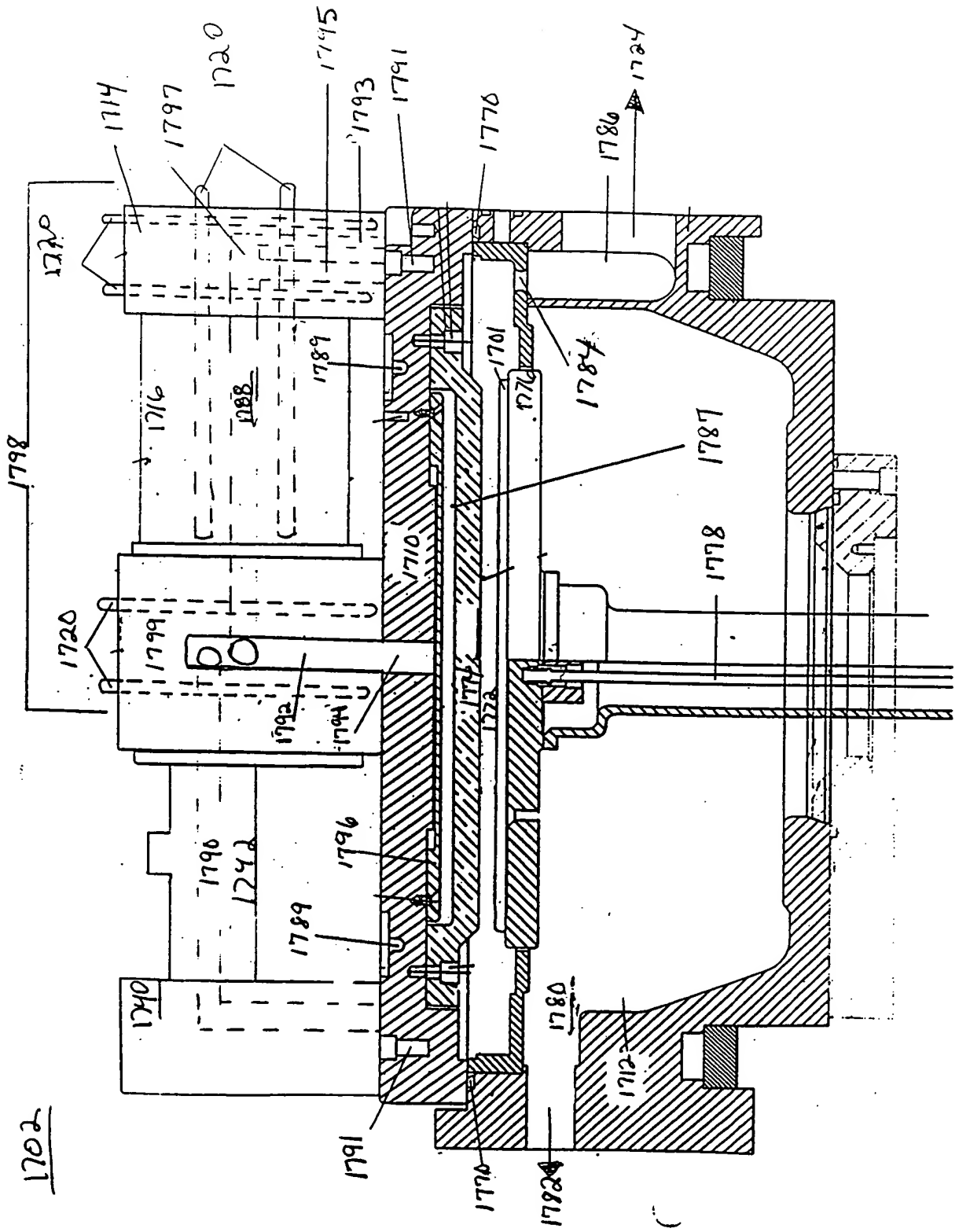


FIGURE 17B

1702



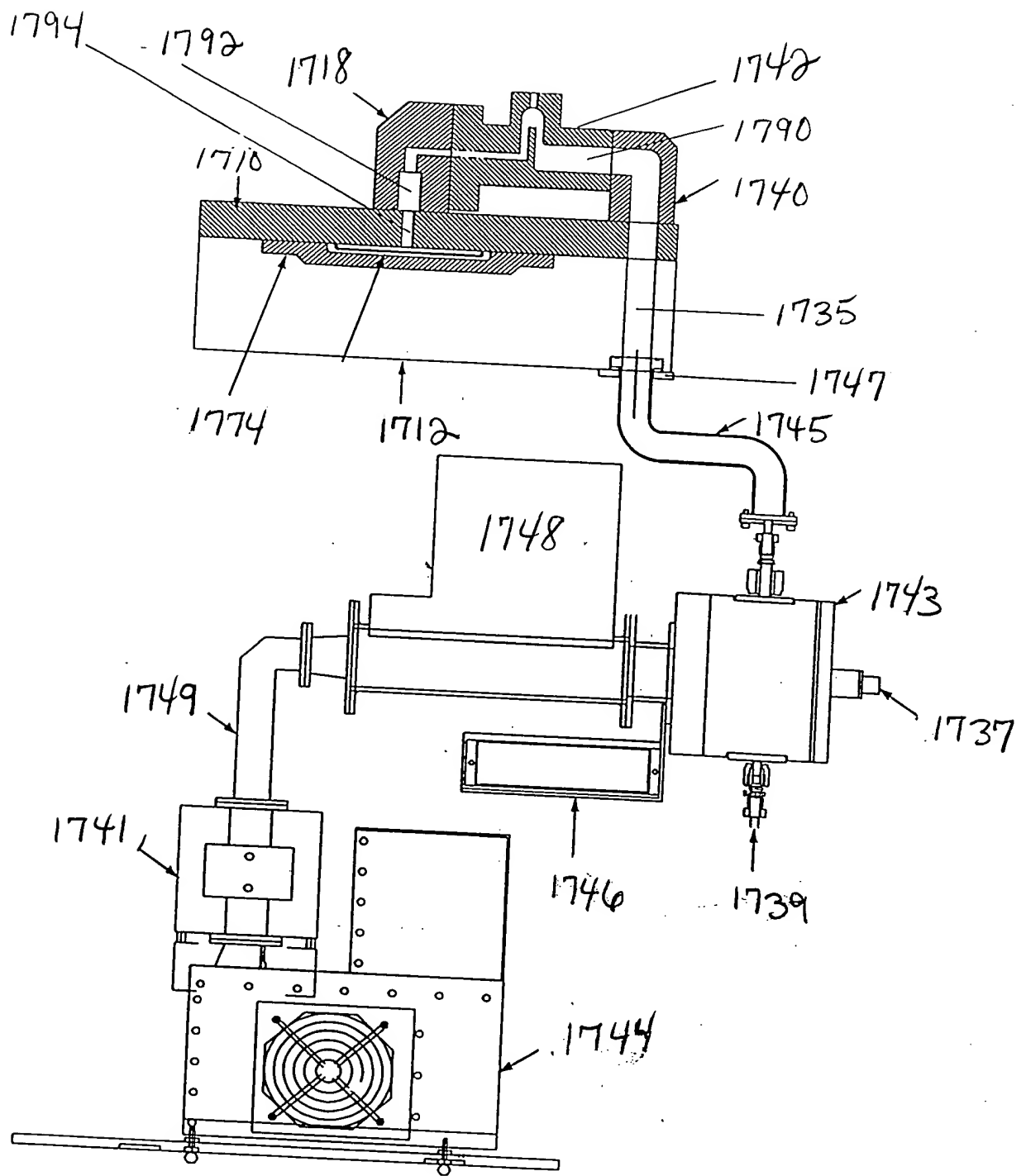


Figure 17C Remote Microwave Plasma Apparatus 1706

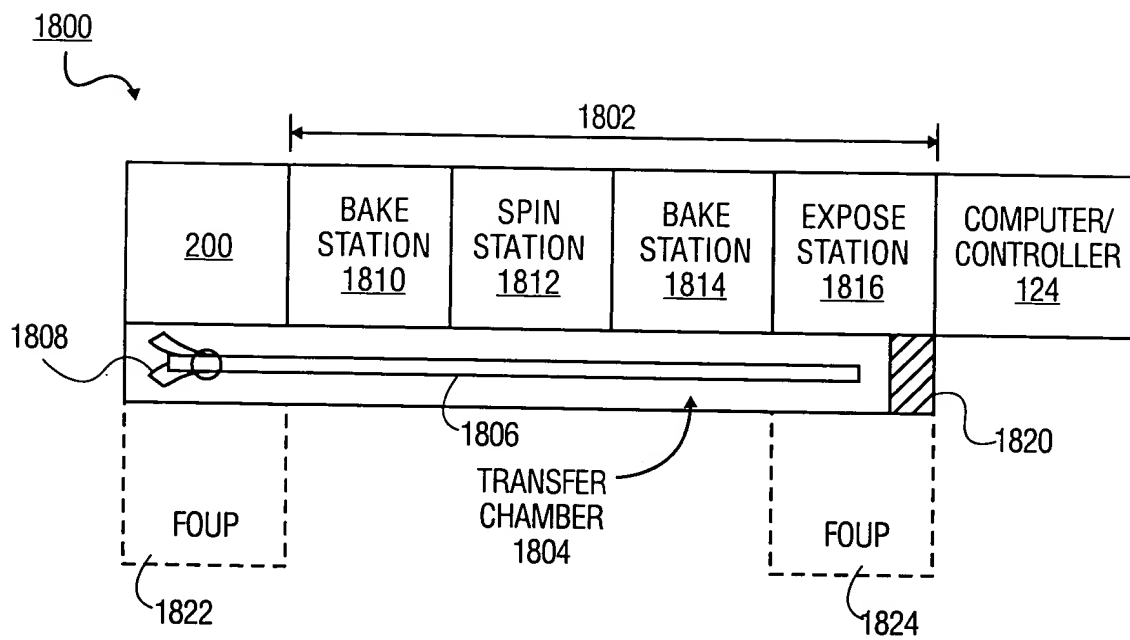


FIG. 18A

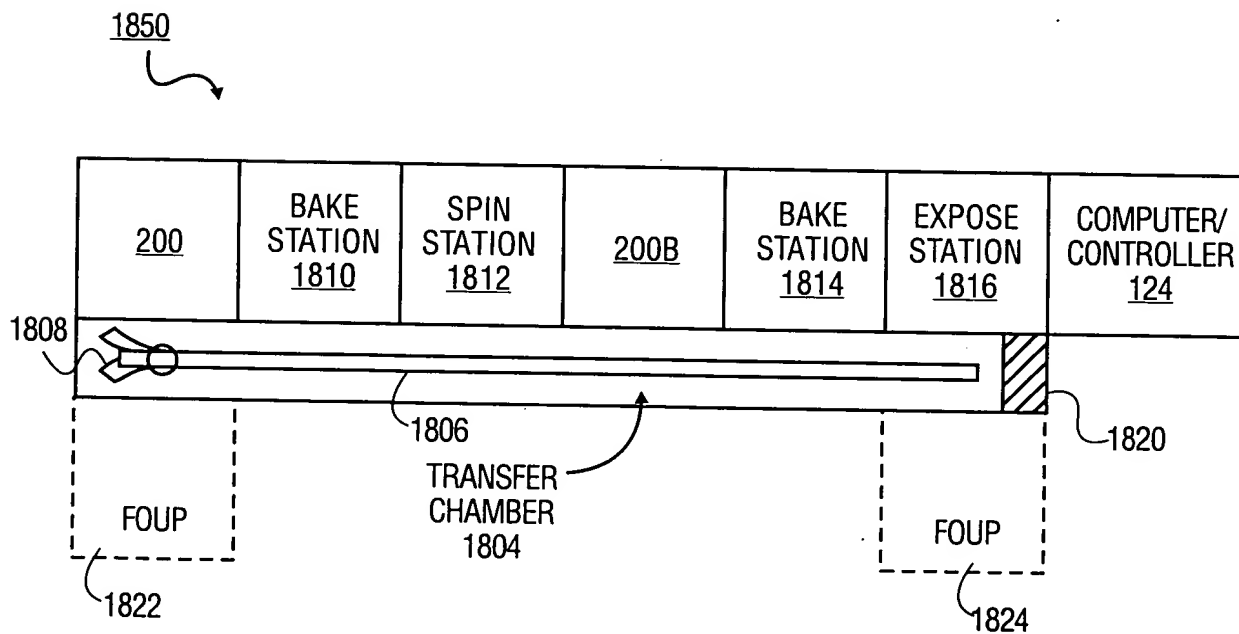
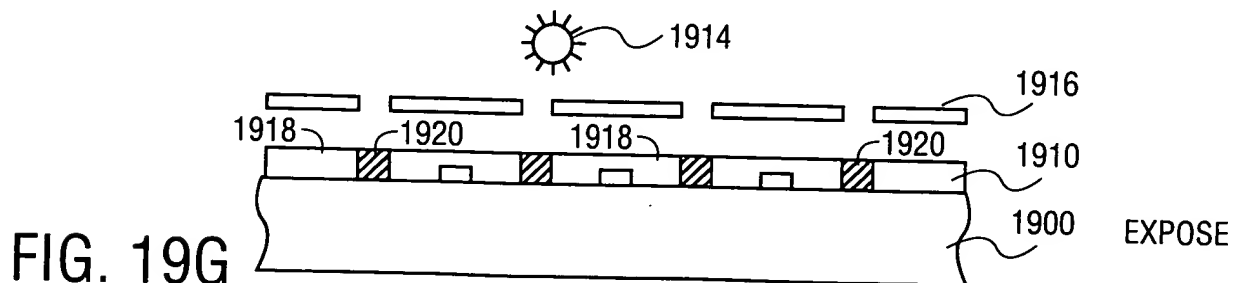
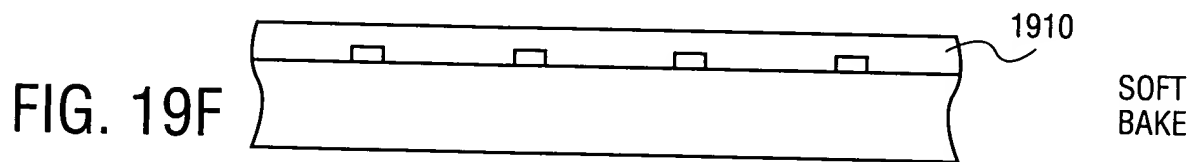
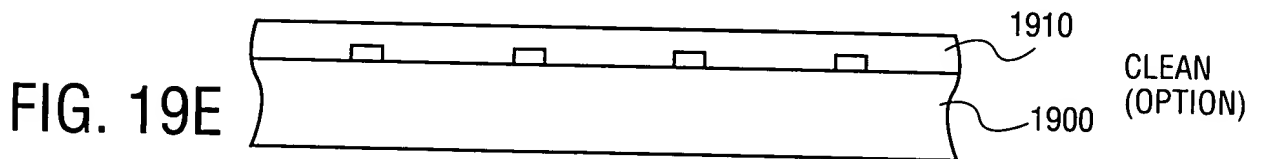
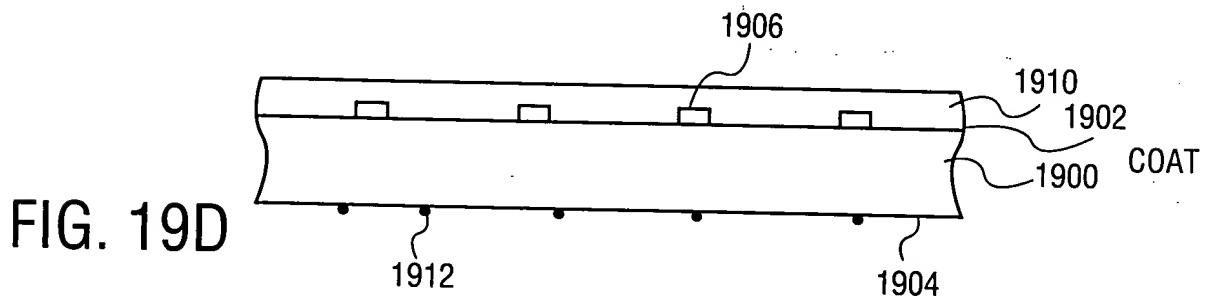
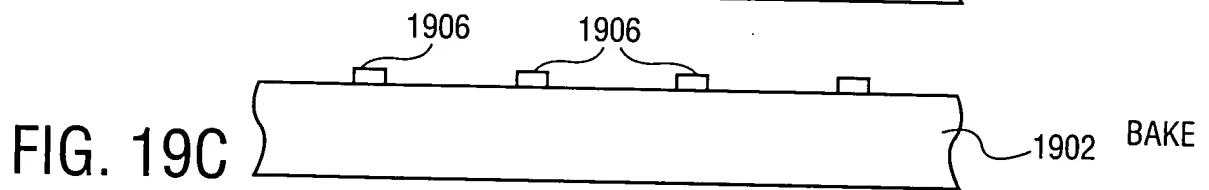
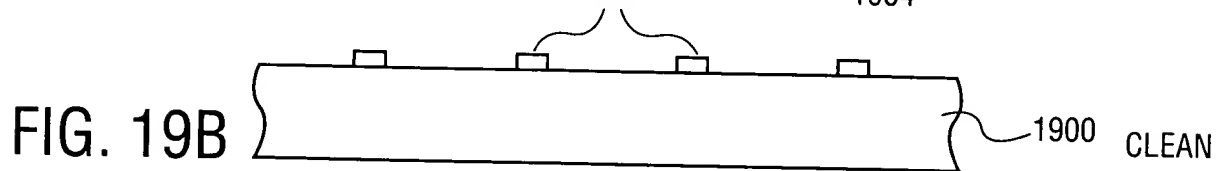
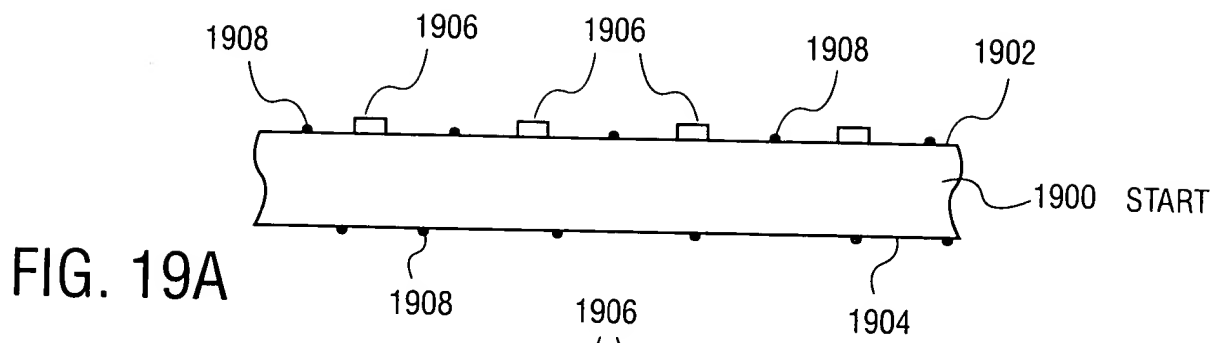


FIG. 18B



124

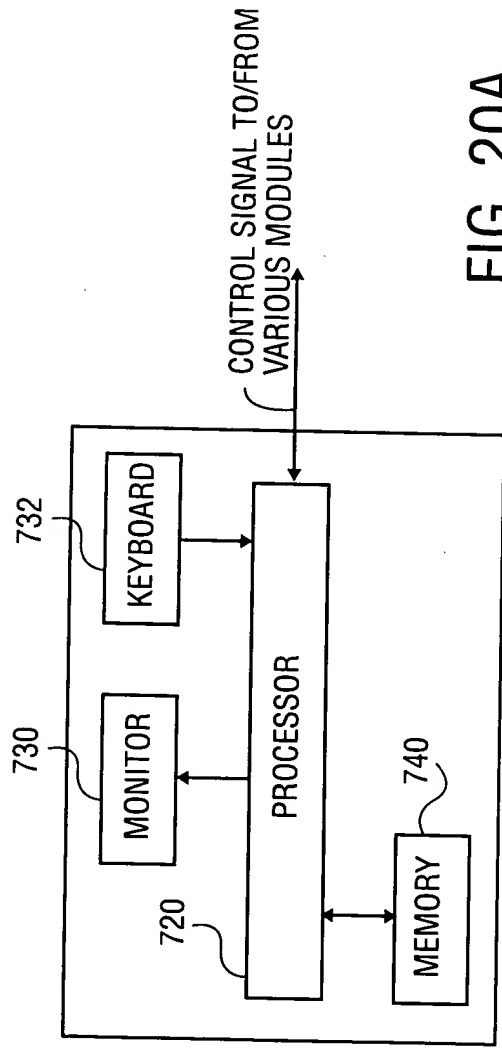


FIG. 20A

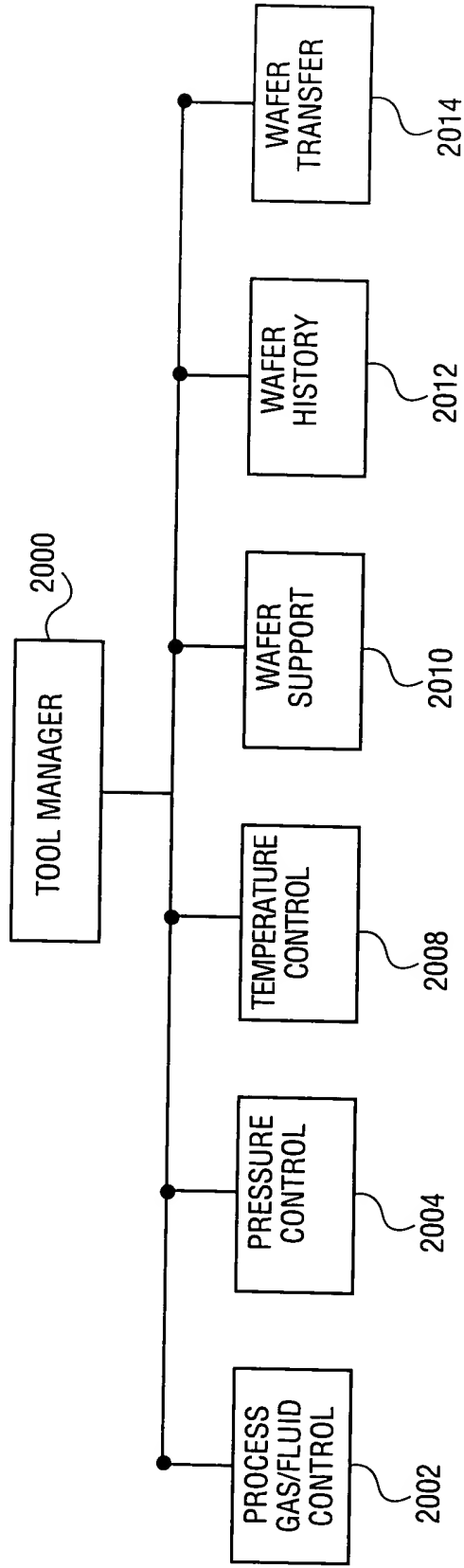


FIG. 20B